

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S1	3988	((catalyst catalytic) with (metal conductive)) and (substrate base wafer) and (carbon near2 nanotube)	US-PGRUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/10/24 16:11
S2	1839	((catalyst catalytic) with (metal conductive)) and (substrate base wafer) and ((carbon near2 nanotube) same (vapor CVD))	US-PGRUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/10/24 16:11
S3	1033	S2 and (((single adj wall \$2) single-wall\$2 SWNT) with (carbon near2 nanotube))	US-PGRUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/10/24 16:13
S4	365	S3 and ((catalyst catalytic) with (support insulat\$3))	US-PGRUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/10/24 16:14
S5	431	S3 and ((catalyst catalytic) with support \$3)	US-PGRUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/10/24 16:14
S6	77	S3 and (((catalyst catalytic) with support \$3) same (oxidiz\$3 oxidat \$3 hydroxylat\$3))	US-PGRUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/10/24 16:17
S7	2	("20030042226").PN.	US-PGRUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2008/10/25 14:28

S8	1840	((catalyst catalytic) with (metal conductive)) and (substrate base wafer) and ((carbon near2 nanotube) same (vapor CVD))	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/10/25 15:37
S9	92	S8 and ((carbon near2 (nanotube nano-tube)) with (direction along) with ((surface plane) near3 (substrate base wafer support\$3)))	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/10/25 15:39
S10	30	S8 and ((carbon near2 (nanotube nano-tube)) with (reduc\$3 near2 (gas source)))	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/10/25 15:45
S11	2	("20050042162").PN.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2008/10/25 15:53
S12	172	S8 and (((catalyst catalytic) with support \$3) same (pattern\$3 etch \$3 shap\$3))	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/10/25 16:18
S13	0	S8 and (((first near2 electrode) same (second near2 electrode) same ((connect\$3 attach\$3) with (nanotube nano-tube))) and ((gate near2 electrode) same (volt volatge)))	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/10/25 16:45
S14	10	S8 and (((first near2 electrode) same (second near2 electrode)) and ((gate near2 electrode) same (volt volatge)))	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/10/25 16:46
S15	2810	(catalyst catalytic) and (substrate base wafer) and ((carbon near2 (nano-tube nanotube)) same (vapor CVD))	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/10/25 16:54

S16	16	S15 and (((first near2 electrode) same (second near2 electrode)) and ((gate near2 electrode) same (volt volatge)))	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2008/10/25 16:54
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